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OHNISHI(10) **Pub. No.: US 2022/0416759 A1**(43) **Pub. Date: Dec. 29, 2022**(54) **PIEZOELECTRIC VIBRATION PLATE,
PIEZOELECTRIC VIBRATION DEVICE, AND
MANUFACTURING METHOD FOR
PIEZOELECTRIC VIBRATION DEVICE****Publication Classification**

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(57) **ABSTRACT**

The piezoelectric vibration plate includes a piezoelectric substrate, a first driving electrode and a second driving electrode formed on main surfaces on both sides of the piezoelectric substrate, and a first mounting terminal and a second mounting terminal respectively connected to the first driving electrode and the second driving electrode. The first and second mounting terminals each have a metal film for mounting purpose formed on the piezoelectric substrate and a metal film for driving purpose formed on the metal film for mounting purpose. The metal films for mounting purpose each include a solder-resistant metal film. The metal films for driving purpose are formed in continuity with the first and second driving electrodes and constitute the first and second driving electrodes.

